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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/830,214	04/22/2004	Se-hoon Oh	5649-1275	9024
20792 7.	590 07/12/2005		EXAMINER	
MYERS BIGEL SIBLEY & SAJOVEC			GARCIA, JOANNIE A	
PO BOX 37428 RALEIGH, NO			ART UNIT PAPER NUMBER	
			2823	

DATE MAILED: 07/12/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

			11.
· .	Application No.	Applicant(s)	
	10/830,214	OH ET AL.	
Office Action Summary	Examiner	Art Unit	
	Joannie A. García	2823	
The MAILING DATE of this communicate Period for Reply	ion appears on the cover sheet wi	th the correspondence address	
A SHORTENED STATUTORY PERIOD FOR THE MAILING DATE OF THIS COMMUNICA*  - Extensions of time may be available under the provisions of 37 after SIX (6) MONTHS from the mailing date of this communica*  - If the period for reply specified above is less than thirty (30) day if NO period for reply is specified above, the maximum statutor - Failure to reply within the set or extended period for reply will, I Any reply received by the Office later than three months after the earned patent term adjustment. See 37 CFR 1.704(b).	TION.  CFR 1.136(a). In no event, however, may a restantion.  ys, a reply within the statutory minimum of thirty period will apply and will expire SIX (6) MON by statute, cause the application to become AB	eply be timely filed  y (30) days will be considered timely.  THS from the mailing date of this communic  ANDONED (35 U.S.C. § 133).	eation.
Status		·	
1) Responsive to communication(s) filed on	n 26 April 2005.		
	This action is non-final.		
3) Since this application is in condition for	– allowance except for formal matte	ers, prosecution as to the merit	ls is
closed in accordance with the practice u	inder <i>Ex parte Quayle</i> , 1935 C.D	. 11, 453 O.G. 213.	
Disposition of Claims			
4)⊠ Claim(s) <u>1-20</u> is/are pending in the appli	cation.		
4a) Of the above claim(s) is/are w			
5)⊠ Claim(s) <u>18</u> is/are allowed.			
6)⊠ Claim(s) <u>1,2,5-14,17,19 and 20</u> is/are re	jected.		
7) Claim(s) 3,4,15 and 16 is/are objected to	-		
8) Claim(s) are subject to restriction			
Application Papers			
9) The specification is objected to by the Ex	caminer.		
10) The drawing(s) filed on is/are: a)		by the Examiner.	
Applicant may not request that any objection	. ,	•	
Replacement drawing sheet(s) including the	- · ·	• •	21(d).
11)☐ The oath or declaration is objected to by	the Examiner. Note the attached	Office Action or form PTO-152	2.
Priority under 35 U.S.C. § 119			
12)⊠ Acknowledgment is made of a claim for f a)⊠ All b)□ Some * c)□ None of:	oreign priority under 35 U.S.C. §	119(a)-(d) or (f).	
1.⊠ Certified copies of the priority doc	uments have been received.		
2. Certified copies of the priority doc		pplication No.	
3. Copies of the certified copies of the		· · ——	)
application from the International	Bureau (PCT Rule 17.2(a)).		
* See the attached detailed Office action fo	r a list of the certified copies not	received.	
·			
Attachment(s)	,		
1) Notice of References Cited (PTO-892)		ummary (PTO-413)	
<ol> <li>Notice of Draftsperson's Patent Drawing Review (PTO-53)</li> <li>Information Disclosure Statement(s) (PTO-1449 or PTO</li> </ol>		)/Mail Date Iformal Patent Application (PTO-152)	
Paper No(s)/Mail Date	6) Other:	—·	

Art Unit: 2823

The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.

Claims 1, 2, 7-10, 13, 14, 17, 19, and 20, are rejected under 35 U.S.C. 102(a) as being anticipated by Iizuka et al (US 2002/0190294 A1).

The rejection is maintained as stated in the Office Action mailed 04-26-05, and as stated below.

Applicant argues that Iizuka et al does not teach crystallizing an HfO<sub>2</sub> dielectric layer on a lower electrode of a capacitor structure in a low temperature plasma treatment at a temperature in a range between about 250 °C and about 450 °C, and that Iizuka et al does not even mention crystallization or a plasma. However, Iizuka et al discloses an ALD deposited HfO<sub>2</sub> dielectric layer 106 on a lower electrode 105 in a low temperature plasma atmosphere at a temperature in a range between about 250 °C and about 400 °C (Figure 13, and Paragraphs 0131, and 0134). Iizuka et al discloses that the dielectric layer 106 can be made of another materials, such as ZrO<sub>2</sub>, among others, besides HfO<sub>2</sub> (Paragraph 0134). Furthermore, Iizuka et al discloses that crystallization of an ALD deposited ZrO<sub>2</sub> dielectric layer is achieved by annealing or heating at a temperature in a range between about 250 °C and about 450 °C (Paragraphs 0076 and 0077), and therefore, formation of a crystallized ALD deposited HfO<sub>2</sub> dielectric layer 106 on a lower electrode 105 of a capacitor structure in a low temperature plasma treatment at a temperature in a range between about 250 °C and about 450 °C would have been achieved in the process of Iizuka et al.

Claims 5, 6, 11, and 12, are rejected under 35 U.S.C. 103(a) as being unpatentable over Iizuka et al as applied to claims 1, 2, 7-10, 13, 14, 17, 19, and 20, above, and further in view of Harada (US 2002/0195643 A1).

The rejection is maintained as stated in the Office Action mailed 04-26-05, and as stated below.

Applicant argues that Harada does not even mention a plasma treatment. However, Harada discloses annealing an HfO<sub>2</sub> dielectric layer in a plasma atmosphere including N<sub>2</sub> (Paragraph 0081). Furthermore, Harada discloses that performing a gas-containing step can be achieved in either a thermal process or a plasma process (Paragraphs 0140 and 0141). Therefore, a plasma treatment would have been mentioned and achieved in the process of Harada.

Applicant argues that Harada does not teach a HfO<sub>2</sub> dielectric layer, and that disclosure of a silicon-containing HfO<sub>2</sub> dielectrics, is not equivalent to HfO<sub>2</sub>. However, the claims are not so limited. Furthermore, Harada discloses a dielectric layer made of HfO<sub>2</sub> (Paragraph 0081, lines 3-4), and annealing the HfO<sub>2</sub> dielectric layer in a plasma atmosphere including N<sub>2</sub> (Paragraph 0081, lines 4-7).

Claims 3, 4, 15, and 16, are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

Claim 18 is allowed.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Joannie García whose telephone number is (571) 272-1861. The examiner can normally be reached on Monday through Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri, can be reached on (571) 272-1855. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

George Fourson Primary Examiner Art Unit 2823

JA**G** July 9, 2005

GFourson Primary Examiner